

EAST - (residual.war...)

File View Edit Window Help

Active

L1: (2879) (deep near trench\$1) or (bottle near trench\$1)

L2: (4644) (deep near trench\$1) or (bottle near trench\$1) or (trench near

L3: (433) 2 and (buried adj plate)

L4: (215) 3 and (anneal\$3 or heat\$3)

L5: (196) 4 and ((upper or top) with (trench or capacitor))

L6: (118) 5 and (shap\$3 or configuration or rectangle or rectangular)

L7: (103) 6 and trench.clm.

L8: (93) 7 and (capacitor.clm. or memory.clm. or (buried adj plate).clm.)

L9: (93) 8 and (etch\$3)

L10: (29) 9 and ((ammonia or KOH or plasma) with etch\$3)

L11: (433) 2 and (buried adj plate)

L12: (349) 11 and (anneal\$3 or heat\$3 or thermal)

L13: (235) 12 and ((etch\$3 or shap\$3 or remov\$3) near (trench or upper or

L14: (0) 13 and ((upper or top) near (rectangle or rectangular))

L15: (220) 13 and trench.clm.

L16: (26) 15 and (rectangular or rectangle)

L17: (9) ("5804851") or ("6004844") or ("6218319") or ("6281068") or ("

L18: (2547) 2 and trench.clm.

L19: (32) 18 and ((wide\$3 or shap\$3 or etch\$3) near ((upper or top) near

L20: (23) 18 and ((wide\$3 or shap\$3 or etch\$3) near ((upper or top) adj

Failed

USPAT:USP:SUB

Events

Default language: OR

High speed processing

18 and ((wide\$3 or shap\$3 or etch\$3) near ((upper or top) adj trench))

Active

Active

Group

Tab

File

	U	I	PT	B	Document ID	Issue Dat	Pages	Title	Current OR	Current XR	Retrieval	Inventor	S	C				
13					US 6660582	20031209	28	Method of forming a	438/245	257/E21.65		Birner, Albert et						
14					B2			vertical field-effect t		2;		al.						
					US 6620699	20030916	8	Method for forming	438/386	257/E21.65		Scholz, Arnd et						
					B2			inside nitride spacer f		5;		al.						
15					US 6503798	20030107	9	Low resistance strap	438/268	257/301;		Divakaruni,						
					B1			for high density trench		257/305;		Ramachandra et al.						
16					US 6403412	20020611	10	Method for in-situ	438/238	257/E21.21		Economikos,						
					B1			formation of bottle sha		8;		Laertis et al.						
17					US 6318384	20011120	37	Self cleaning method of	134/22.1	134/1.1;		Khan, Anisul et						
					B1			forming deep trenches i		134/1.2;		al.						
18					US 6180975	20010130	13	Depletion strap	257/306	257/296;		Radens, Carl J. et						
					B1			semiconductor memory de		257/301;		al.						
19					US 5989975	19991123	8	Method for	438/424	257/E21.54		Kuo, Chien-Li						
					A			manufacturing shallow t		9;								
20					US 5395786	19950307	7	Method of making a DRAM	438/248	257/E21.65		Hsu, Louis L. et						
					A			cell with trench capaci		1;		al.						
21					US 5298790	19940329	7	Reactive ion etching	257/622	257/301;		Harmon, David L.						
					A			buffer mask		257/534;		et al.						
22					US 5118384	19920602	5	Reactive ion etching	438/717	204/192.37		Harmon, David L.						
					A			buffer mask		;		et al.						
23					US 4980747	19901225	8	Deep trench isolation	257/513	257/520;		Hutter, Louis N.						
					A			with surface contact to		257/E21.53		et al.						

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Current

Next

Ready

100%

28 Active

12: (1618) 1 and (damp or bottle)

☛ L2: (1618) 1 and (deep or bottle)

☛ L3: (1134) 2 and ((buried adj plate\$1) or (deep near trench\$2))

☛ L4: (611) 3 and ((upper or lower

L5: (599) 4 and erch\$3

L6: (386) 5 and (ammonia or plasma or KOH or  $\text{NH}_52$  or hydroxide

L7: (337) 6 and trench\$2.clm.

L8: (246) 7 and ((upper or top) near (trench or capacitor))

☒ L91: (156) 8 and (shape) of configuration

111: (47) 10 and (shape63 or configuration)

113: (7) 11 and rectangular

113: (142) 7 and (etchs3) near (am

U14: (85) 13 and (etch\$3 near (trench or capacitor))

2 L15: (83) 14 and (etch\$3 near trench\$2)

L16: (12) 15 and (etch\$3 near (upper or

L17: (88) 3 and (buried adj plate).c

L18: (34) 17 and dopant and anneal\$3

L19: (15) 18 and (shape3 or configuration)

10-10-1941 (13) 5 and (c) 1941 10-10-1941

0.5	0.5	0.5	0.5	0.5
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032 USPAT-UP-PGP-98

**Definición**

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3 and (trench$3 near (rectangle or rectangular))
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	U	I	PT	P	Document ID	Issue Dat	Pages	Title	Current OF	Current RA	Retrieval	Inventor	S	C	3	4	5	6	7	8	9	10	11	12	13	14	15	16	17	18	19	20	21	22	23	24	25	26	27	28	29	30	31	32	33	34	35	36	37	38	39	40	41	42	43	44	45	46	47	48	49	50	51	52	53	54	55	56	57	58	59	60	61	62	63	64	65	66	67	68	69	70	71	72	73	74	75	76	77	78	79	80	81	82	83	84	85	86	87	88	89	90	91	92	93	94	95	96	97	98	99	100	101	102	103	104	105	106	107	108	109	110	111	112	113	114	115	116	117	118	119	120	121	122	123	124	125	126	127	128	129	130	131	132	133	134	135	136	137	138	139	140	141	142	143	144	145	146	147	148	149	150	151	152	153	154	155	156	157	158	159	160	161	162	163	164	165	166	167	168	169	170	171	172	173	174	175	176	177	178	179	180	181	182	183	184	185	186	187	188	189	190	191	192	193	194	195	196	197	198	199	200	201	202	203	204	205	206	207	208	209	210	211	212	213	214	215	216	217	218	219	220	221	222	223	224	225	226	227	228	229	230	231	232	233	234	235	236	237	238	239	240	241	242	243	244	245	246	247	248	249	250	251	252	253	254	255	256	257	258	259	260	261	262	263	264	265	266	267	268	269	270	271	272	273	274	275	276	277	278	279	280	281	282	283	284	285	286	287	288	289	290	291	292	293	294	295	296	297	298	299	300	301	302	303	304	305	306	307	308	309	310	311	312	313	314	315	316	317	318	319	320	321	322	323	324	325	326	327	328	329	330	331	332	333	334	335	336	337	338	339	340	341	342	343	344	345	346	347	348	349	350	351	352	353	354	355	356	357	358	359	360	361	362	363	364	365	366	367	368	369	370	371	372	373	374	375	376	377	378	379	380	381	382	383	384	385	386	387	388	389	390	391	392	393	394	395	396	397	398	399	400	401	402	403	404	405	406	407	408	409	410	411	412	413	414	415	416	417	418	419	420	421	422	423	424	425	426	427	428	429	430	431	432	433	434	435	436	437	438	439	440	441	442	443	444	445	446	447	448	449	450	451	452	453	454	455	456	457	458	459	460	461	462	463	464	465	466	467	468	469	470	471	472	473	474	475	476	477	478	479	480	481	482	483	484	485	486	487	488	489	490	491	492	493	494	495	496	497	498	499	500	501	502	503	504	505	506	507	508	509	510	511	512	513	514	
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